

**AMENDMENTS IN THE CLAIMS**

Please cancel claims 1 through 33 without prejudice or disclaimer as to their subject matter, amend claims 34 through 38 and newly add claims 39 through 46 as follows:

Claims 1-33. (Canceled)

1           34.(Currently Amended) A method of manufacturing a bubble-jet type ink jet printhead,  
2 comprising ~~the steps of~~:  
3           depositing, patterning, and etching a resistive material on a silicon substrate;  
4           depositing, patterning, and etching an individual signal line over a portion of said resistive  
5 material;  
6           depositing a first electrically insulating layer over said silicon substrate;  
7           etching a hole in said first electrically insulating layer exposing a portion of said resistive  
8 material absent of said individual signal line;  
9           depositing, patterning, and etching a common signal line, said common signal line being in  
10 electrical contact with said resistive material via said hole in said first electrically insulating layer;  
11           depositing a second electrically insulating layer over said silicon substrate;  
12           etching through a portion of said first and second insulating layers to expose a portion of said  
13 individual signal line in a region absent of said resistive material;  
14           depositing, patterning, and etching a film to form a plurality of ~~chamber~~ barrier walls, a first  
15 of said plurality of ~~chamber~~ barrier walls being on top of a substantial portion of said individual  
16 signal line, and a second of said plurality of ~~chamber~~ barrier walls being parallel to said first ~~chamber~~

17 ~~wall of said plurality of barrier walls~~, said second ~~chamber wall~~ of said plurality of barrier walls  
18 being on an opposite side of said hole in said first insulating layer than said first ~~chamber walls of~~  
19 said plurality of barrier walls; and

20 attaching a nozzle plate to a top portion of said plurality of ~~chamber~~ barrier walls, said nozzle  
21 plate being perforated by a plurality of nozzle holes, one of said plurality of nozzle holes being  
22 directly above said hole in said first insulating layer.

1 35. (Currently Amended) The method of claim 34, ~~wherein~~ said resistive material is patterned  
2 to be “P” shaped.

1 36.(Currently Amended) The method of claim 35, ~~wherein~~ said individual line covers a  
2 straight portion of said “P” shaped resistive layer.

1 37. (Currently Amended) The method of claim 36, ~~wherein~~ said hole in said first insulating  
2 layer is located over a center of a curved portion of said “P” shaped resistive layer.

1 38. (Currently Amended) The method of claim 37, ~~wherein~~ one unit heater is located between  
2 one side of said center of said curved portion of said resistive layer and said straight portion of said  
3 resistive layer and another unit heater is located between another side of said center of said curved  
4 portion of said resistive layer and said straight portion.

1 39. (New) A method of manufacturing a bubble-jet type ink jet printhead, comprising:

2 forming a plurality of resistive heater elements comprised of patterned resistive material on  
3 a substrate;

4 forming a patterned electrode layer on the substrate, the patterned electrode layer being  
5 electrically connected to the resistive heater elements;

6 forming barrier walls over the substrate, the barrier walls separating pairs of patterned  
7 resistive heater elements from each other; and

8 attaching a nozzle plate to a top of the plurality of barrier walls, the nozzle plate being  
9 perforated by a plurality of nozzle holes, each nozzle hole being disposed above a portion of the  
10 substrate between a pair of patterned resistive heater elements, each nozzle hole also being disposed  
11 between a pair of adjacent barrier walls.

1 40. (New) The method of claim 39, further comprising forming an insulating layer over the  
2 substrate, over the resistive heater elements and over the patterned electrode layer, the plurality of  
3 barrier walls being formed on the insulating layer.

1 41. (New) The method of claim 39, the resistive heater elements being formed in pairs,  
2 wherein barrier walls serve to separate one pair of resistive heating elements from another adjacent  
3 pair of resistive heater elements.

1 42. (New) The method of claim 39, said electrode layer is deposited so that each pair of  
2 resistive heaters are electrically connected in series.

1           43. (New) A method of manufacturing a bubble-jet type ink jet printhead, comprising:  
2           forming a plurality of resistive heater elements comprised of patterned resistive material on  
3           a substrate;  
4           forming a patterned first electrode layer on the substrate, the patterned first electrode layer  
5           being electrically connected to the resistive heater elements;  
6           forming a first insulating layer over the substrate, the plurality of resistive heater elements  
7           and the patterned first electrode layer;  
8           etching a hole perforating the first insulating layer to expose a portion of a resistive heater  
9           element;  
10          forming a second electrode layer over the first insulating layer, said second electrode layer  
11          being formed in said hole to form electrical contact to said resistive heater element;  
12          forming barrier walls over the substrate, the barrier walls separating pairs of patterned  
13          resistive heater elements from each other; and  
14          attaching a nozzle plate to a top of the plurality of barrier walls, the nozzle plate being  
15          perforated by a plurality of nozzle holes.

1           44. (New) The method of claim 43, further comprising forming a second insulating layer  
2           over the first insulating layer and over the second electrode layer, wherein the barrier walls are  
3           formed on the second insulating layer.

1           45. (New) The method of claim 43, said hole being formed over a portion of a resistive  
2           heater that is not covered by the first electrode layer.

1           46. (New) The method of claim 44, further comprising etching back a portion of the second  
2           insulating layer to expose a portion of the first electrode layer.